

INFORMATION DISCLOSURE CITATION PTO-1449		ATTY. DOCKET NO. P132-US		SERIAL NO. Not Yet Assigned			
		APPLICANT Jim Dunphy, et al.					
		FILING DATE Herewith		GROUP Not Yet Assigned			
U.S. PATENT DOCUMENTS							
EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE	
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	U.S. Pub App No. 2002/0063322	5/30/02	Robbins, et al.				
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De	"Lubrication of Digital Micromirror Devices" Henck, Tribology Letters 3 (1997) 239-247						
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	"Measurement of Micromoto Dynamics in Lubricating Fluids" Deng IEEE						
De	"Friction and Wear studies on Lubricants and materials Applicable to MEMS" Shigehisa Suzuki, IEEE 1991, pgs 143-147						
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EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

INFORMATION DISCLOSURE CITATION APR 28 2005 PTO-1449 SHEET 1 OF 2		ATTY. DOCKET NO. P132-US		SERIAL NO. 10/811,449			
		APPLICANT Dunphy, et al.					
		FILING DATE 3/26/04		GROUP Not Yet Assigned			
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<i>DL</i> <div style="border-left: 1px solid black; height: 100px; margin: 0 auto; width: 20px;"></div>	2004/0012838	1/22/04	Huibers				
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